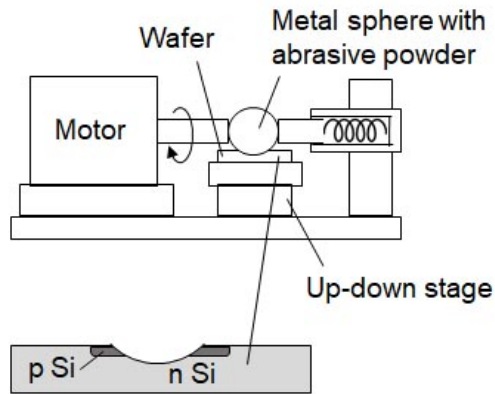
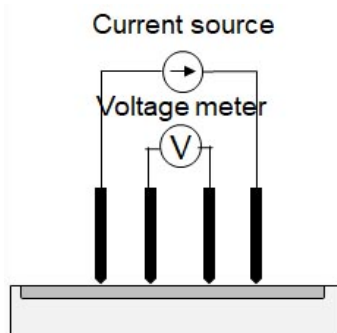


12 Various measurement method other than optics



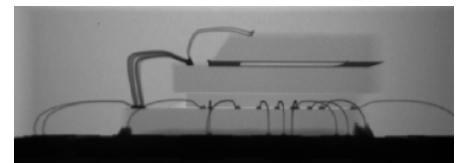
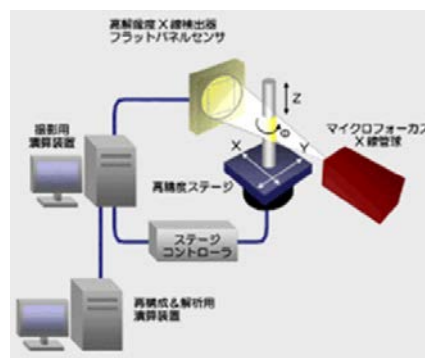
p Si is colored to measure depth after polishing in round shape by spherical drill



Measurement of sheet resistance by 4 probes



Atomic force microscope (AFM) (Park Systems NX-20)



Micro X ray CT (used in clean room 1F) and cross-sectional image of 3D accelerometer



Scanning electron microscope (SEM)



X ray diffraction